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## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s):

HAMAMATSU, et al.

Serial No.:

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Filed:

January 18, 2002

For:

APPARATUS AND METHOD FOR INSPECTING DEFECTS

Group:

2877

Examiner:

M. Stafira

Conf. No.:

9567

## **AMENDMENT**

Commissioner for Patents P.O. Box 1450 Alexandria, Virginia 22313-1450

November 16, 2005

Sir:

Please amend the above-identified application as listed below and as set forth on the following pages:

## Amendments to the Claims

Remarks are included following the amendments